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Analysis of characteristic parameters of a plasma ion source and of ion-assisted deposited optical thin films

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D. E. Morton and V. Fridman, "Measurement and Correlation of Ion Beam Current Density to Moisture Stability of Oxide Film Stacks Fabricated by Cold Cathode Ion Assisted Deposition," *41st Annual Technical Conference Proceedings*, Society of Vacuum Coaters, pp. 297–302 (1998).

O. Zabeida, J. E. Klemberg-Sapieha, L. Martinu, and D. E. Morton, "Ion Bombardment Characteristics During the Growth of Optical Films Using a Cold Cathode Ion Source," *42nd Annual Technical Conference Proceedings*, Society of Vacuum Coaters, pp. 267–272 (1999).

D. E. Morton, "The Effects of Pumping Speed on the Operation of a Cold Cathode Ion Source," *43rd Annual Technical Conference Proceedings*, Society of Vacuum Coaters, pp. 207–211 (2000).

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